CLAIMS

What is claimed is:

- 1. A semiconductor device, comprising:
- at least one contact pad positioned on a surface of the semiconductor device adjacent an edge thereof; and
- a layer comprising dielectric material on at least a portion of said surface, said layer having a notch formed therein which exposes at least a portion of said at least one contact pad.
- 2. The semiconductor device of claim 1, wherein an edge portion of said layer adjacent said edge of the semiconductor device tapers from a surface of said layer toward said edge of the semiconductor device.
- 3. The semiconductor device of claim 2, wherein said edge portion of said layer comprises a bevel.
- 4. The semiconductor device of claim 1, wherein said at least one notch is tapered from a surface of said layer toward said surface of the semiconductor device.
- 5. The semiconductor device of claim 1, wherein said layer covers substantially all of said surface.
- 6. The semiconductor device of claim 1, wherein said at least one notch substantially surrounds said at least one contact pad.
 - 7. The semiconductor device of claim 1, including a plurality of contact pads.
- 8. The semiconductor device of claim 7, wherein at least some of said contact pads are located adjacent said edge.

- 9. The semiconductor device of claim 8, wherein said layer includes regions extending laterally between adjacent contact pads of said at least some contact pads.
- 10. The semiconductor device of claim 1, wherein said dielectric material comprises a polymer.
- 11. The semiconductor device of claim 1, wherein said dielectric material comprises a photoimageable material.
- 12. A protective layer for a semiconductor device, comprising:
 a substantially planar member comprising dielectric material; and
 at least one notch formed adjacent an edge of said substantially planar member, said at least one
 notch being configured to expose at least a portion of a corresponding contact pad of the
 semiconductor device upon positioning the protective layer over a surface of the
 semiconductor device.
 - 13. The protective layer of claim 12, comprising a bevel along said edge.
- 14. The protective layer of claim 12, wherein at least one edge of said at least one notch is beveled.
- 15. The protective layer of claim 12, wherein said dielectric material comprises a polymer.
- 16. The protective layer of claim 12, wherein said dielectric material comprises a photoimageable material.
- 17. The protective layer of claim 12, including a plurality of notches located along said edge.

- 18. The protective layer of claim 12, wherein said substantially planar member is configured to substantially cover a surface of the semiconductor device upon assembly therewith.
- 19. The protective layer of claim 12, wherein said substantially planar structure is configured to cover only a portion of a surface of the semiconductor device adjacent an edge thereof proximate to which at least one contact pad is located upon assembly of the protective layer with the semiconductor device.
- 20. The protective layer of claim 12, wherein said at least one notch is formed in said edge.
- 21. The protective layer of claim 12, wherein said at least one notch is configured to substantially surround the corresponding contact upon assembly of the protective layer with the semiconductor device.